

Metal chalcogenide nanorings for temperature-strain dual-mode sensing

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Characterization methods.

Scanning electron microscope (SEM, JEOL JSM-7800F, Japan), transmission electron microscope (TEM, JEOL 2100Plus, Japan), high resolution transmission electron microscope (HRTEM, JEOL 2100F, Japan) coupled with energy dispersive X-ray (EDX) spectroscopy were used to investigate the materials morphological, compositional, and structural features. X-ray diffraction (XRD, Rigaku SmartLab, Japan) and X-ray photoelectron spectroscopy (XPS, PHI 5000 VersaProbe, Japan) were performed to reveal the materials crystal phase and structure. Raman spectra (Horiba HR800, France) were obtained with a 532 nm laser. The metallic properties of the $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings were studied with a semiconductor characterization system (Keithley 4200).

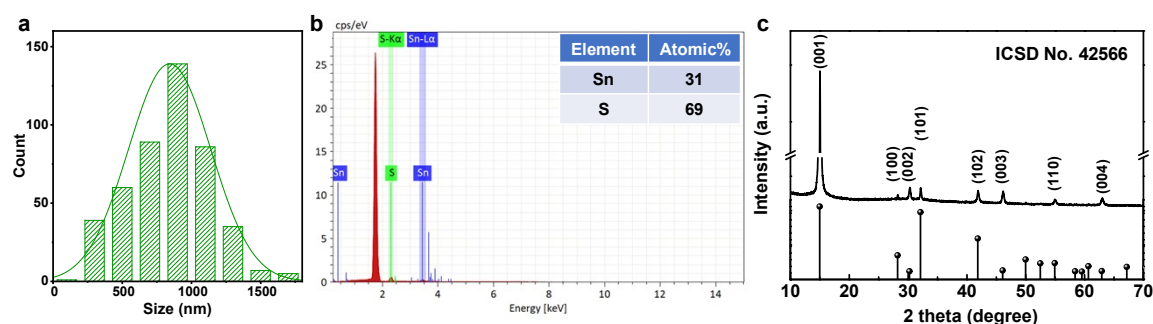


Fig. S1 EDX analysis (a) and XRD pattern (b) of SnS₂ nanoplates.

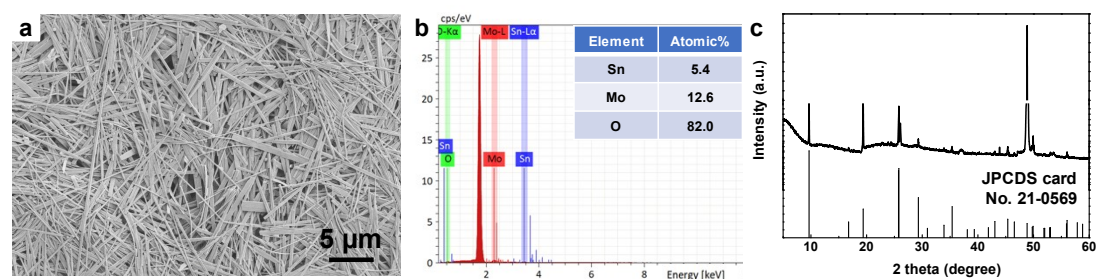


Fig. S2 SEM image (a), EDX analysis (b), and XRD pattern (c) of Sn_{0.3}Mo_{0.7}O₃ nanorods.

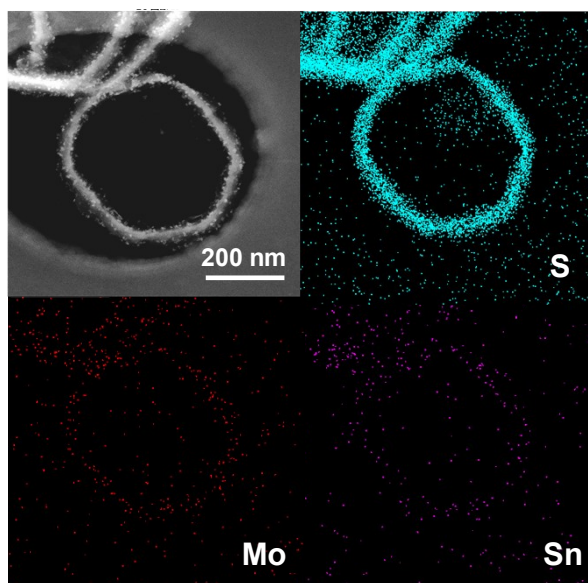


Fig. S3 STEM image and EDX mapping of $\text{Sn}_{1-x}\text{Mo}_x\text{S}_2$ nanorings.

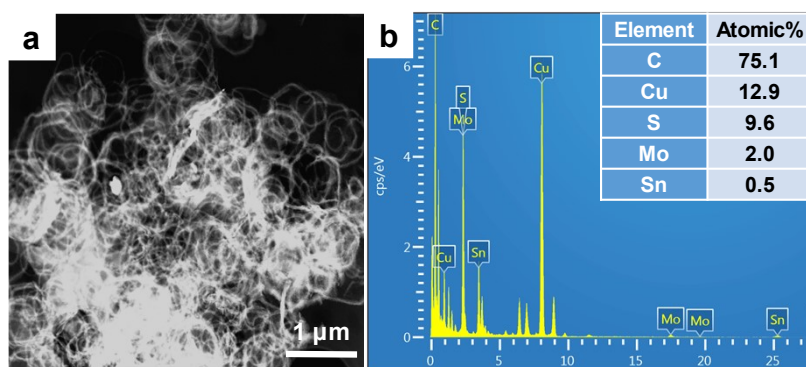


Fig. S4 STEM image (a) and EDX spectrum (b) of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings. A mean value of ~ 0.8 was determined for x .

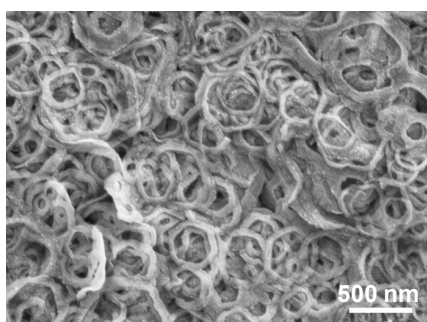


Fig. S5 The SEM images of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings were synthesized 12 mg $\text{Sn}_{0.3}\text{Mo}_{0.7}\text{O}_3$ as precursors.

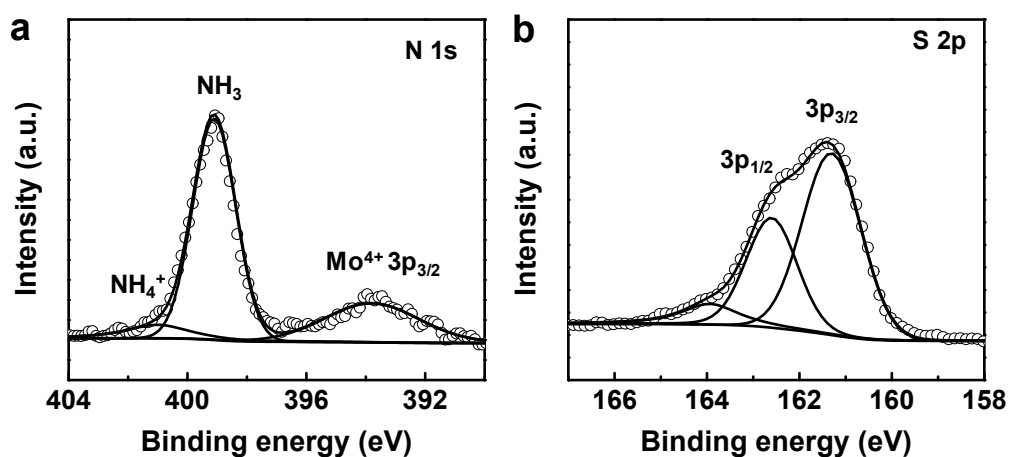


Fig. S6 XPS N 1s (a) and S 2p (b) spectra of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings.

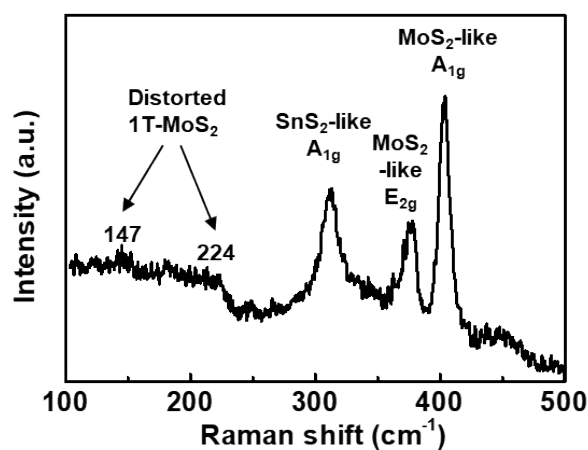


Fig. S7 Raman spectrum of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings.

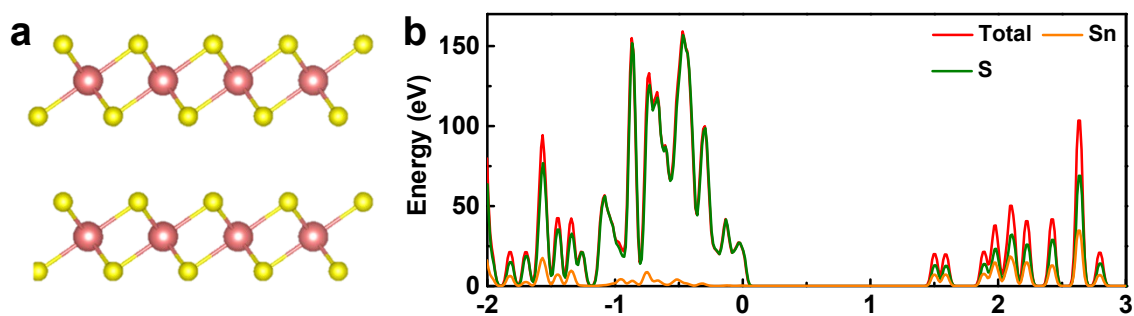


Fig. S8 Optimized crystal structure (a) and DOS (b) of a SnS_2 , showing the semiconducting property. The Fermi level is assigned at 0 eV.

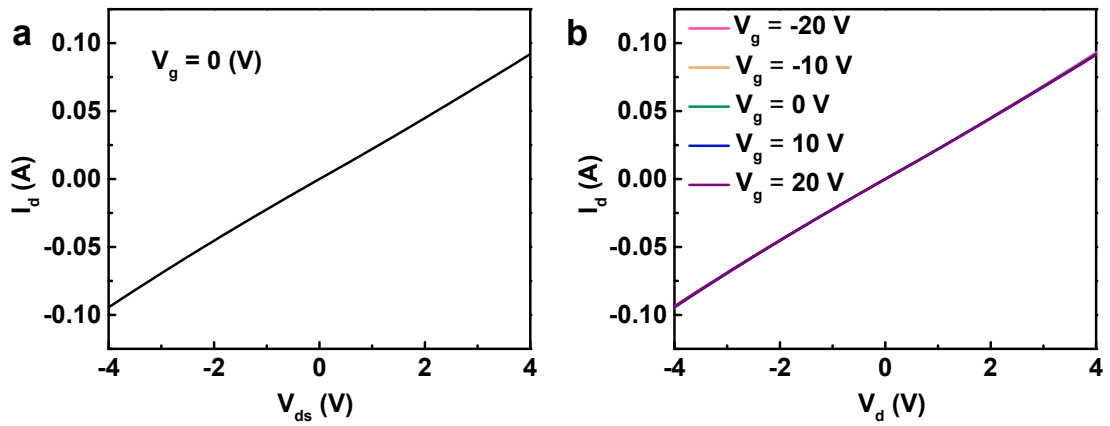


Fig. S9 Drain current (I_d) characteristics of back-gated TFTs based $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings for drain-source voltages (V_{ds}) varied from -4 to 4 V at 0 V gate voltage (V_g). The I_d - V_{ds} curves of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings at varied V_g from -20 to 20 V.

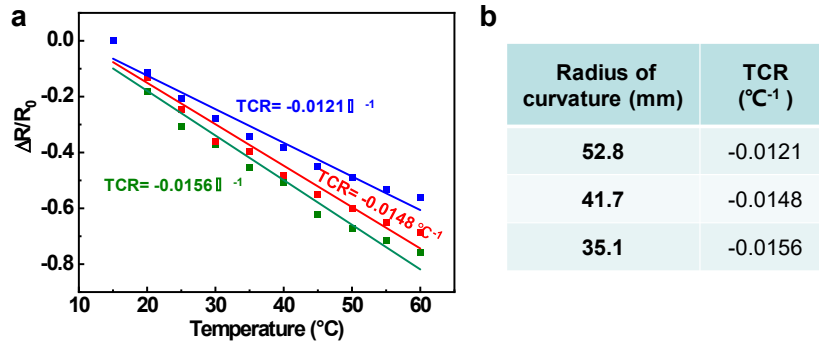


Fig. S10 (a) Calculation of temperature coefficient of resistance. (b) TCR of temperature sensors with different radius of curvature.

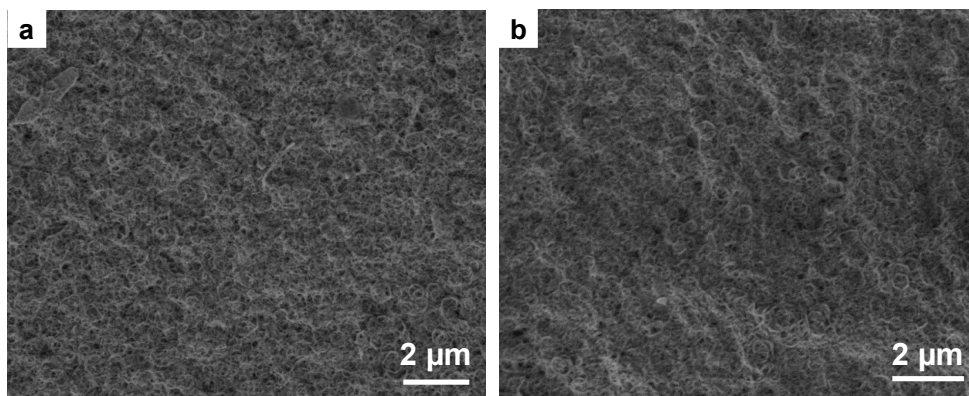


Fig. S11 The SEM images of $\text{Sn}_{0.2}\text{Mo}_{0.8}\text{S}_2$ nanorings based strain sensor before (a) and after (b) 300 cyclic bending tests.

Table 1 Comparison of various inorganic materials-based thermoresistive temperature sensors.

Material type	Material	Fabrication method	Temperature range (°C)	Sensitivity	Stretchability	Ref.
	Sn _{0.2} Mo _{0.8} S ₂	inkjet printing	25-85	-0.013 °C ⁻¹	flexible	This work
	rGO fiber	wet spinning	30-80	-0.00636 °C ⁻¹	flexible	1
	rGO-PU/PDMS	wet spinning	25-50	-0.01185 °C ⁻¹	50%	2
	rGO film	spray coating	0-100	-	3%	3
	graphene-(PEDOT:PSS)/PU	inkjet printing	35-45	-0.0006 °C ⁻¹	-	4
	rGO/parylene	spray coating	22-70	-0.0083 °C ⁻¹	flexible	5
	rGO/PET	spray coating	30-100	-0.006345 °C ⁻¹	flexible	6
	PEI-rGO/polyimide	Spray coating	25-45	-0.013 °C ⁻¹	bending angle:40°	7
	graphene/polyorganosiloxane aerogels	freeze drying	20-100	-	80%	8
Carbon	graphene nanoribbons	writing or spraying	30-80	-0.0127 °C ⁻¹	curvature radius: 1 cm	9
	graphene/porous elastic polyurethane	dip coating	20-100	-0.00815 °C ⁻¹	50%	10
	rGO-Pu	spin coating	-	0.009 °C ⁻¹	70%	11
	CNT	printing	21-80	~0.0025 °C ⁻¹	flexible	12
	graphene	CVD	-	0.0042 °C ⁻¹	40%	13
	Ti ₃ C ₂ T _x /cellulose	vacuum filtration	27-140	~0.00222 °C ⁻¹	flexible	14
	LIG/MXene-Ti ₃ C ₂ T _x @EDOT	laser-induced	26-45	0.0052 K ⁻¹	flexible	15
metal nanowire	Ag NWs	electrospinning	30-45	0.0003 °C ⁻¹	flexible	16
	Ag NWs-PI	filtration	-20-20	0.0033 °C ⁻¹	flexible	17
	MoS ₂	CVD	27-120	0.01-0.02 K ⁻¹	flexible	18
	MoS ₂	-	-	0.0057 K ⁻¹	-	19
semiconductor	MoTe ₂	-	-	0.0064 K ⁻¹	-	19
	MoS ₂ -graphene	coating	-	-	flexible	20
	MoS ₂	printing	-	0.0102 °C ⁻¹	80%	21
	MoS ₂	inkjet printing	30-70	-0.0095 °C ⁻¹	flexible	22

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